

Can be integrated into an end effector, ideal for wafer mapping

MAPPING SENSOR – DELIVERING PRECISION IN THE SMALLEST POSSIBLE SPACE

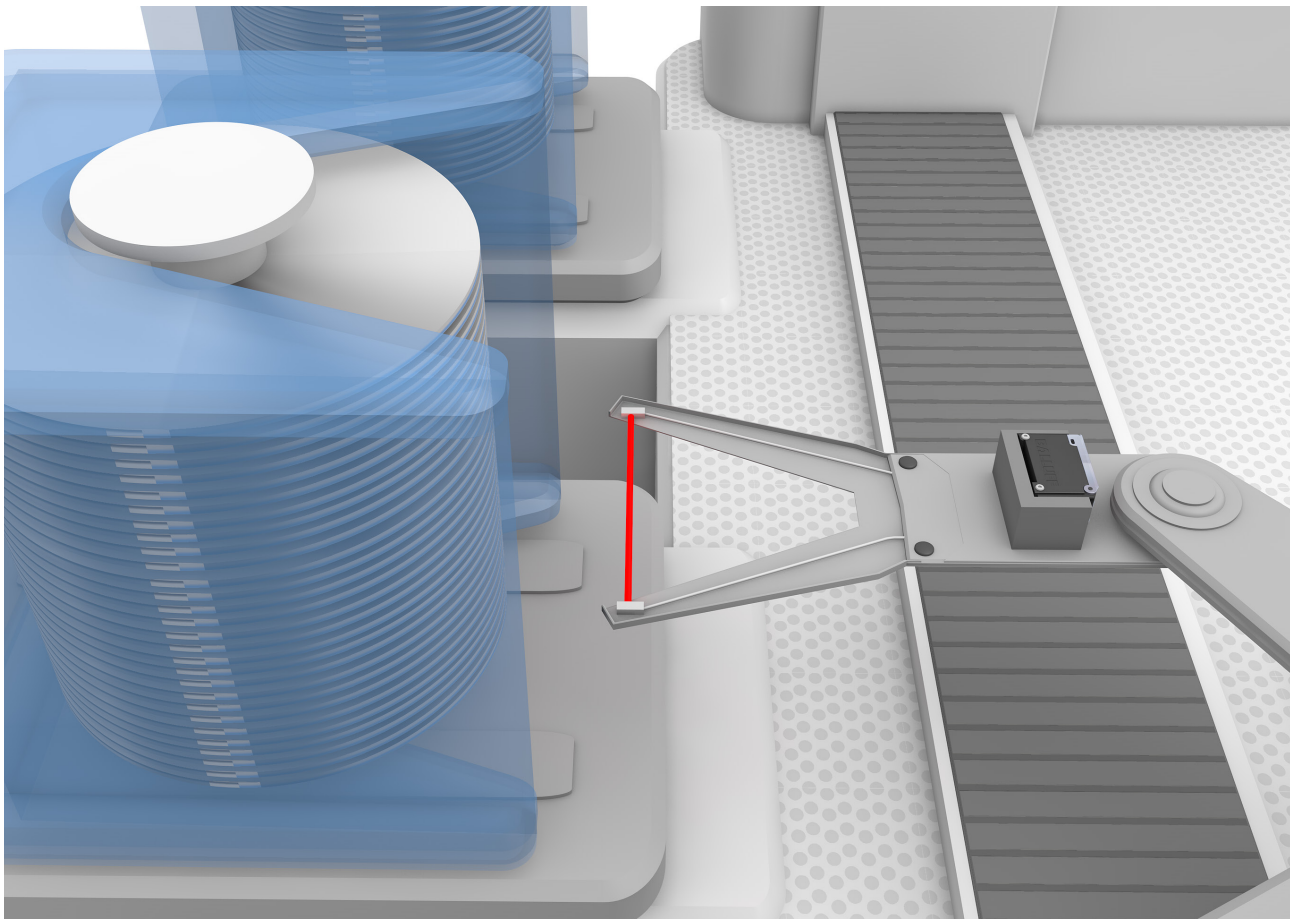
For your wafer mapping needs, Balluff offers a highly precise photoelectric sensor which integrates perfectly into an end effector. Especially designed for extremely thin end effectors, our mapping sensor features an extremely controlled and focused light spot with outstanding homogeneity. This allows the sensor to detect wafers even just a few μm thick with extreme precision. And you can be confident that it will reliably detect full slots, doubled wafers or tilted wafers will be reliably detected at all times.

The mapping sensor is based on the photoelectric Micromote technology, which combines an extremely small optical sensor head with an external processor

unit (amplifier) and connects them via a highly flexible cable. This means you can adapt the mapping sensor to any mechanical installation situation, like other Micromote sensors.

Features

- Very compact, extremely flexible sensor cable
- Multi-functional sensor head
- Flexible adaptation to the respective application using an BAE external amplifier



MICROMOTE –
OPTICAL SENSOR HEADS



	BOH00EZ
Series	R002
Dimension	2.4 x 1.5 x 7 mm
Interface	For switching amplifier
Principle of operation	Optical sensor head
Principle of optical operation	Through-beam sensor
Beam characteristic	Divergent
Light type	LED infrared
Range	0...800 mm
Connection	Cable with connector, M8 female, 3-pole, 1 m, PFA
Housing material	LCP, natural
Material sensing surface	Epoxy
Approval/conformity	CE

ACCESSORIES



FOR PNP NO/NC	BAE00NE	BAE00NF
FOR NPN NO/NC	BAE00PR	BAE00PT
Description	Amplifiers for Micromote – optical sensor heads, 2 m PVC cable, 5 x 0.14 mm ²	Amplifiers for Micromote – optical sensor heads, M8 male, 4-pin